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on November 4, 2009.

TOWNSEND and TOWNSEND and CREW LLP

By: /Sherry Soares/
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PATENT
Docket No.: A7600P1/T51700
Client Ref. No.: 7600/P1/DSM/HDP/CVD/JPFEIFER
TTC No.: 016301-051700US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Hemant P. Mungekar, et al.

Patent No.:

Issued:

Application No.: 10/660,813

Filed: September 12, 2003

For: REACTIVE ION ETCHING FOR
SEMICONDUCTOR DEVICE
FEATURE TOPOGRAPHY
MODIFICATION

Customer No.: 57385

Confirmation No.: 7055

Examiner: Rodney Glenn McDonald

Art Unit: 1795

**RESPONSE TO NOTICE TO FILE
CORRECTED APPLICATION PAPERS**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Commissioner:

Pursuant to the Notice to File Corrected Application Papers mailed on
November 29, 2009, enclosed are the following to be made of record in the above-identified
application:

- 1) Replacement Drawing Sheet
- 2) Annotated Drawing Sheet Showing Changes
- 3) Copy of Notice to File Corrected Application Papers

Application No. 10/660,813
Response to Notice to File Corrected Application Papers
dated November 4, 2009
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PATENT

No fees are believed due with this response, however, the Commissioner is hereby authorized to charge any additional fees or credit any overpayment in connection with this paper to Deposit Account No. 20-1430.

Respectfully submitted,

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